

IN THE CLAIMS

This listing of claims will replace all prior versions and listings of claims in the application.

Listing of Claims:

1. (Currently Amended) A micro terminal (91) with electrical conduction between said micro terminal and an electrode of an electronic device or an inspection device, comprising a columnar contactor (91a, 91e) in contact with the electrode, wherein

said contactor (91a, 91e) has a spring structure that is elastically deformed by being pressed against the electrode, and said contactor (91a, 91e) has a protrusion (1t) protruding outwardly at its end in contact with the electrode, and

said protrusion (1t) is shaped to have a part of a sphere or a paraboloid of revolution.
2. (Currently Amended) The micro terminal according to claim 1, wherein said contactor (91a, 91e) has a spiral spring structure.
3. (Currently Amended) The micro terminal according to claim 1, wherein said contactor (91a, 91e) has a structure in which a plurality of meandering springs are disposed from a perimeter portion to a central portion of said contactor.
4. (Currently Amended) The micro terminal according to claim 1, wherein a perimeter portion of said columnar contactor (91a, 91e) has a tubular ring structure.
5. (Currently Amended) The micro terminal according to claim 1, wherein said micro terminal (91) has said contactor (91a, 91e) at each of opposing ends in contact with the electrode.
6. (Currently Amended) The micro terminal according to claim 1, wherein said protrusion (1t) has a V-shaped groove opening toward the direction in which said protrusion protrudes.
7. (Currently Amended) The micro terminal according to claim 1, wherein said micro terminal (91) includes nickel or a nickel alloy.
8. (Currently Amended) The micro terminal according to claim 1, wherein said micro terminal (91) has a coat layer including a precious metal or an alloy of a precious metal or polytetrafluoroethylene gold.

9. (Currently Amended) A method of fabricating the micro terminal according to claim 1, wherein the contactor (91a, 91e) of said micro terminal (91) is fabricated by a method including the steps of:

- forming a resin mold by X-ray lithography;
- forming a layer including a metal material at said resin mold on an electrically conductive substrate by electroforming;
- polishing or grinding;
- forming a resin mold on said layer including a metal material by lithography;
- electroforming a layer including a metal material at said resin mold to form a protrusion protruding outwardly;
- removing said resin molds; and
- removing said electrically conductive substrate.

10. (Currently Amended) A method of fabricating the micro terminal (91) according to claim 1, wherein the contactor (91a, 91e) of said micro terminal (91) is fabricated by a method including the steps of:

- forming a resin mold by a metal mold;
- forming a layer including a metal material at said resin mold on an electrically conductive substrate by electroforming;
- polishing or grinding;
- forming a resin mold on said layer including a metal material by lithography;
- electroforming a layer including a metal material at said resin mold to form a protrusion protruding outwardly;
- removing said resin molds; and
- removing said electrically conductive layer.

11. (Currently Amended) The method of fabricating the micro terminal according to claim 9 or 10, wherein said protrusion (11) formed is provided with a V-shaped groove formed by cutting with a dicer.

12. (Currently Amended) A contact sheet including the micro terminal (91) according to claim 1, having a hollow electrode (91b) penetrating the sheet in a thickness direction and said

contactor (~~91a, 91e~~) on said hollow electrode (~~91b~~), wherein said hollow electrode (~~91b~~) has a hollow portion for a spring of said contactor (~~91a, 91e~~) to make a stroke.

13. (Currently Amended) The contact sheet according to claim 12, wherein said hollow electrode (~~91b~~) and said contactor (~~91a, 91e~~) are joined by resistance welding.
14. (Currently Amended) A socket for inspection including the micro terminal (~~91~~) according to claim 1, wherein said socket is used for inspection of semiconductor in land grid array arrangement.
15. (Original) An inspection device including the socket according to claim 14.
16. (Original) A method of inspecting semiconductor using the socket according to claim 14.
17. (Currently Amended) A connector for installation including the micro terminal (~~91~~) according to claim 1, wherein said connector is connected to a land electrode.
18. (Original) An electronic device including the connector according to claim 17.
19. (New) The method of fabricating the micro terminal according to claim 10, wherein said protrusion formed is provided with a V-shaped groove formed by cutting with a dicer.